

NanoScan

NexTech FAS

NanoScan automated optical inspection (AOI) technology employs highly accurate and sensitive detection of problem-causing particles and pattern defects during FPD manufacture, providing submicron particle inspection for the company's AOI platforms. Through the use of NanoScan-enabled equipment, such as the company's NexTStar and the FPDStar, manufacturers can identify and map particle and pattern defects in the active matrix display as well as defects in the intricate circuits surrounding the active matrix. This can all be accomplished on a single platform and at resolutions as small as 300nm, claims the company. The technology will be used primarily within the FPD industry and will be focused on the emerging OLED technology of both glass and flexible substrates. The technology will also be used for TFT/LCD displays, touch-screen substrates, and solar panels. NexTech FAS, Austin, TX USA; ph 512/833-0740, www.nextechfas.com.

Web Site: <http://www.nextechfas.com>